

Application Data Sheet

10/588698
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Application Information

Application Type:: Regular
Subject Matter:: Utility
CD-ROM or CD-R?:: None
Computer Readable Form (CRF)?:: No
Title:: METHOD OF MANUFACTURING A
SEMICONDUCTOR DEVICE AND METHOD
OF ETCHING AN INSULATING FILM
Attorney Docket Number:: 039262-0156
Request for Early Publication?:: No
Request for Non-Publication?:: No
Suggested Drawing Figure:: 6
Total Drawing Sheets:: 6
Small Entity?:: Yes
Petition included?:: No
Secrecy Order in Parent Appl.?:: No

Applicant Information

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Representative Information

Representative Customer Number::	22428	
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Domestic Priority Information

Application::	Continuity Type::	Parent Application::	Parent Filing Date::
This Application	National Stage of	PCT/JP2005/001513	02/02/2005

Foreign Priority Information

Country::	Application number::	Filing Date::	Priority Claimed::
Japan	2004-32607	02/09/2004	Yes

Assignee Information

Assignee Name::

Foundation for Advancement of International
Science